

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	2067	(plasma adj etch\$4 adj apparatus)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:27
S2	277	S1 and (organic near5 material)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:29
S3	153	S2 and (in\$1organic)	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:33
S4	24	S3 and (high-frequency adj power)	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:04
S5	28	S3 and (high-frequency same power)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:30
S6	9	S5 and (ioniza\$4)	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:06
S7	1	S5 and (parallel adj plate near5 electrode)	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:06
S8	8	S6 and electrode	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:06
S9	7	S8 and bias	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:07
S10	7	S9 and (nitrogen or hydrogen)	US-PGPUB; USPAT	OR	OFF	2007/08/15 12:59
S11	6	S10 and ammonia	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:08
S12	3	((("20030080091") or ("20020042204") or ("5272417"))).PN.	US-PGPUB; USPAT	OR	OFF	2006/07/21 16:34
S13	2067	(plasma adj etch\$4 adj apparatus)	US-PGPUB; USPAT	OR	OFF	2006/07/26 10:40
S14	277	S13 and (organic near5 material)	US-PGPUB; USPAT	OR	OFF	2006/07/26 10:40

S15	153	S14 and (in\$1organic)	US-PGPUB; USPAT	OR	OFF	2006/07/26 10:40
S16	28	S15 and (high-frequency same power)	US-PGPUB; USPAT	OR	OFF	2006/07/26 10:40
S17	9	S16 and (ioniza\$4)	US-PGPUB; USPAT	OR	OFF	2006/07/26 10:44
S18	0	S16 and (ioniza\$4 adj energy)	US-PGPUB; USPAT	OR	OFF	2006/07/26 10:45
S19	9399	216/58,67,41,83,438/736,638,637,713,778,713.ccls.	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:05
S20	2067	(plasma adj etch\$4 adj apparatus)	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S21	277	S20 and (organic near5 material)	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S22	153	S21 and (in\$1organic)	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S23	28	S22 and (high-frequency same power)	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S24	9	S23 and (ioniza\$4)	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S25	8	S24 and electrode	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S26	7	S25 and bias	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:06
S27	2	S19 and S26	US-PGPUB; USPAT	OR	OFF	2006/07/26 16:07
S28	2247	(plasma adj etch\$4 adj apparatus)	US-PGPUB; USPAT	OR	OFF	2007/04/12 10:53
S29	304	S28 and (organic near5 material)	US-PGPUB; USPAT	OR	OFF	2007/04/12 10:53
S30	2320	(plasma adj etch\$4 adj apparatus)	US-PGPUB; USPAT	OR	OFF	2007/08/15 13:00

S31	14	S30 and (molecular adj gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 13:05
S32	1	S30 and (ionization adj accelerating adj gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:21
S33	2	((("5211804") or ("6777325")).PN.	USPAT; USOCR	OR	OFF	2007/08/15 14:22
S34	2320	(plasma adj etch\$4 adj apparatus)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:28
S35	34	S34 and (ratio same nitrogen near5 argon)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:44
S36	0	S34 and (ratio same nitrogen near5 argon adj gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:28
S37	2	S34 and (ratio same oxygen near5 argon adj gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:29
S38	1436	S34 and (ratio nitrogen near5 argon)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:30
S39	2249	S34 and (ratio nitrogen near5 argon gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:30
S40	315	S34 and (organic near5 material)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:30
S41	176	S40 and (in\$1organic)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:30
S42	30	S41 and (high-frequency same power)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:30
S43	4	S42 and (nitrogen same argon)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:35
S44	30	S42 and (nitrogen same argon gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:35
S45	30	S42 and (ratio near5 nitrogen same argon gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:35
S46	2256	S34 and (ratio of nitrogen to argon gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:43

S47	2254	S34 and (ratio nitrogen to argon gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:44
S48	2196	S34 and (ratio adj nitrogen adj argon gas gas)	US-PGPUB; USPAT	OR	OFF	2007/08/15 14:45
S49	10	S48 and (etch same organic adj film)	US-PGPUB; USPAT	OR	OFF	2007/08/15 15:20
S50	1	"20020108929"	US-PGPUB; USPAT	OR	OFF	2007/08/15 15:21
S51	1	("20020108929").PN.	US-PGPUB; USPAT	OR	OFF	2007/08/16 08:28

3/ 20/ 2008 3:01:54 PM

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